

## ABSTRACT OF THE DISCLOSURE

A device manufacturing apparatus includes a discharge head discharging a liquid containing a functional material, a stage supporting a substrate on which the liquid is discharged, and which is capable of moving relative to the discharge head, a carrier  
5 carrying the substrate, a detector detecting a discharge condition of the liquid which is discharged from a discharge nozzle formed in the discharge head, and a controller executing a detection operation by the discharge device during a carrying operation of the substrate.